

ELECTROLYTIC POLISHING APPARATUS, ELECTROLYTIC POLISHING METHOD, AND  
WAFER SUBJECT TO POLISHING

Inventor: Takeshi Nogami et al.  
Docket No. 075834.00509

Robert J. Depke, Holland & Knight LLC - (312) 263-3600

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FIG. 1

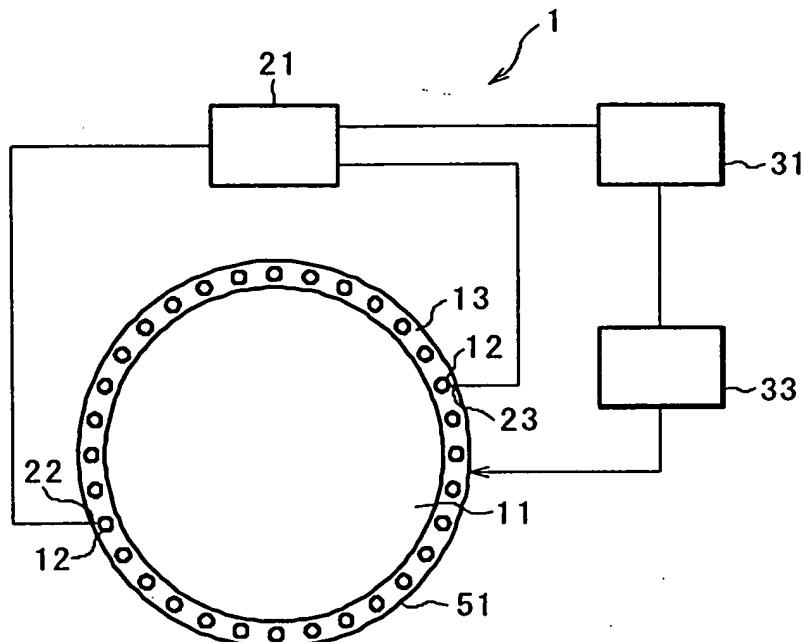
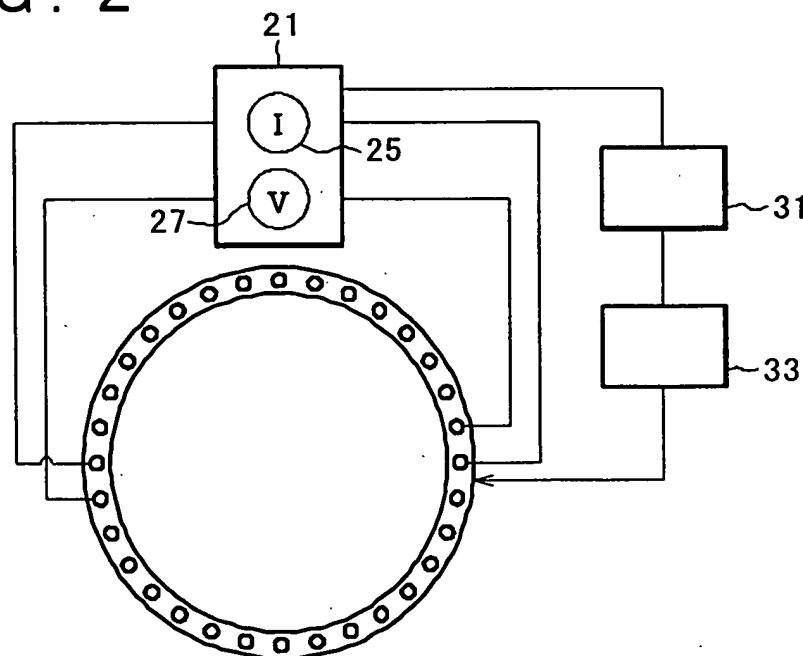


FIG. 2



ELECTROLYTIC POLISHING APPARATUS, ELECTROLYTIC POLISHING METHOD, AND  
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FIG. 3

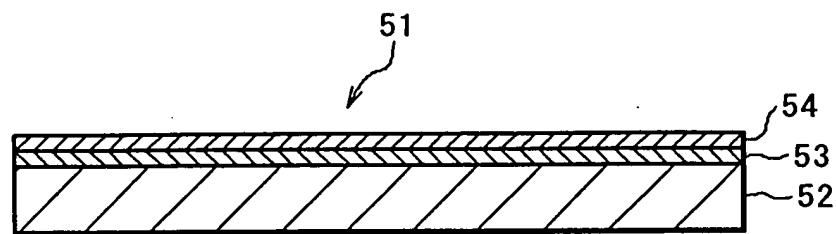
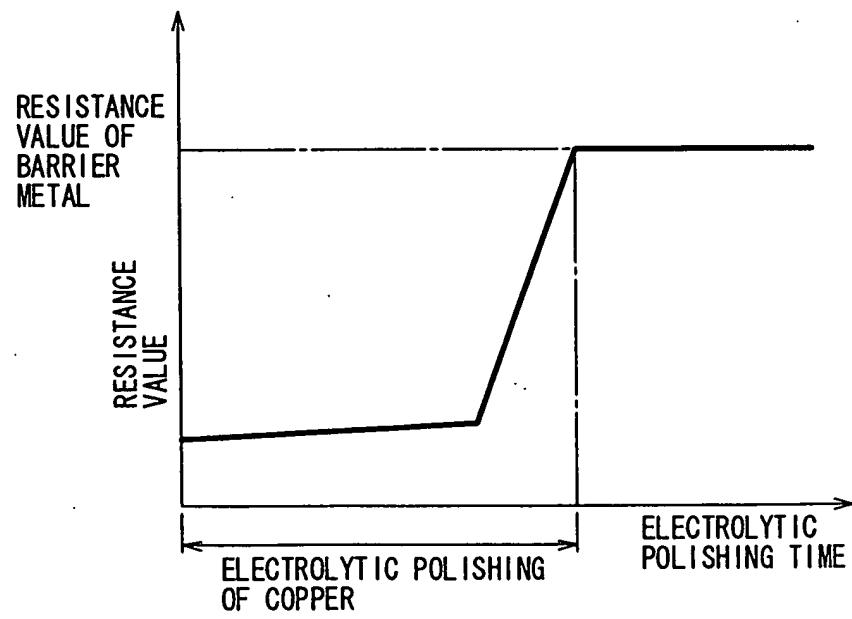


FIG. 4



ELECTROLYTIC POLISHING APPARATUS, ELECTROLYTIC POLISHING METHOD, AND  
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FIG. 5

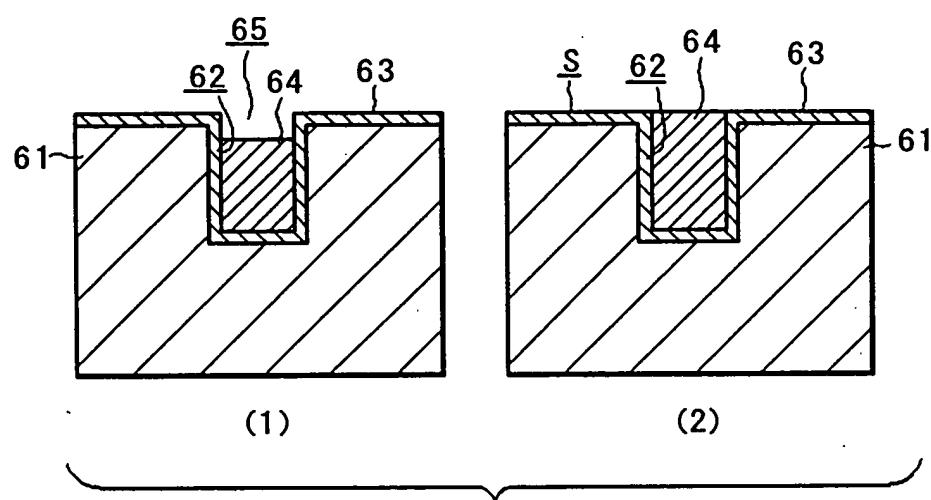


FIG. 6

